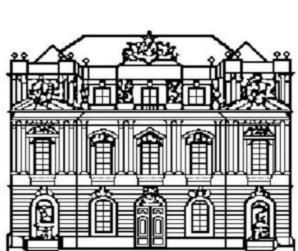


A Micro-Fabricated Segmented Ion Trap For Quantum Computation

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arrangements in two

layers.





Electrodes for

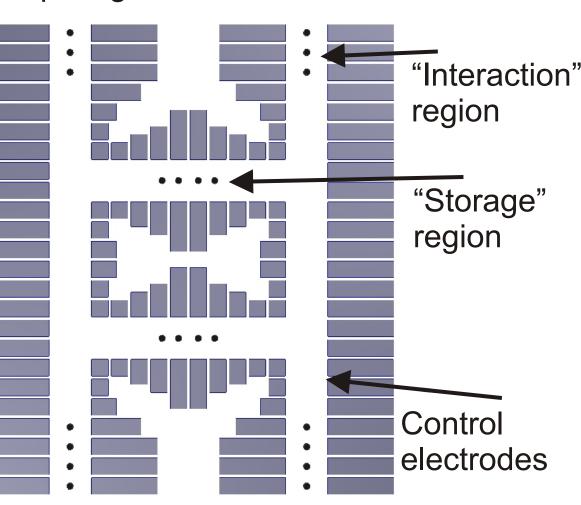
compensation

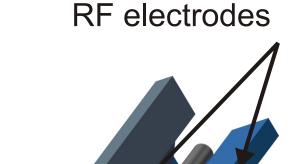
purpose

Motivation

The first proposal for ion-trap quantum computation involved confining a string of ions in a linear Paul trap, using their electronic states as qubit logic levels, and transferring quantum information between ions through their mutual Coulomb interation. In recent years, all the elementary requirements for quantum computation have been demonstrated in such a system. However, manipulating a increasing number of ions in a conventional linear ion trap becomes extremely technologically difficult, and scaling arguments suggest that this scheme is limited to computations on tens of ions.

In 2002, Kielpinski, Monroe and Wineland proposed a "quantum chargecoupled device" architecture which seeks to make ion trap quantum computing scalable

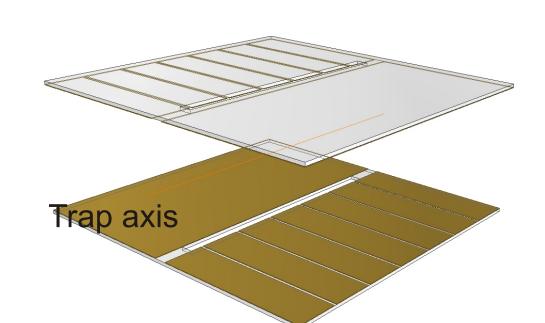


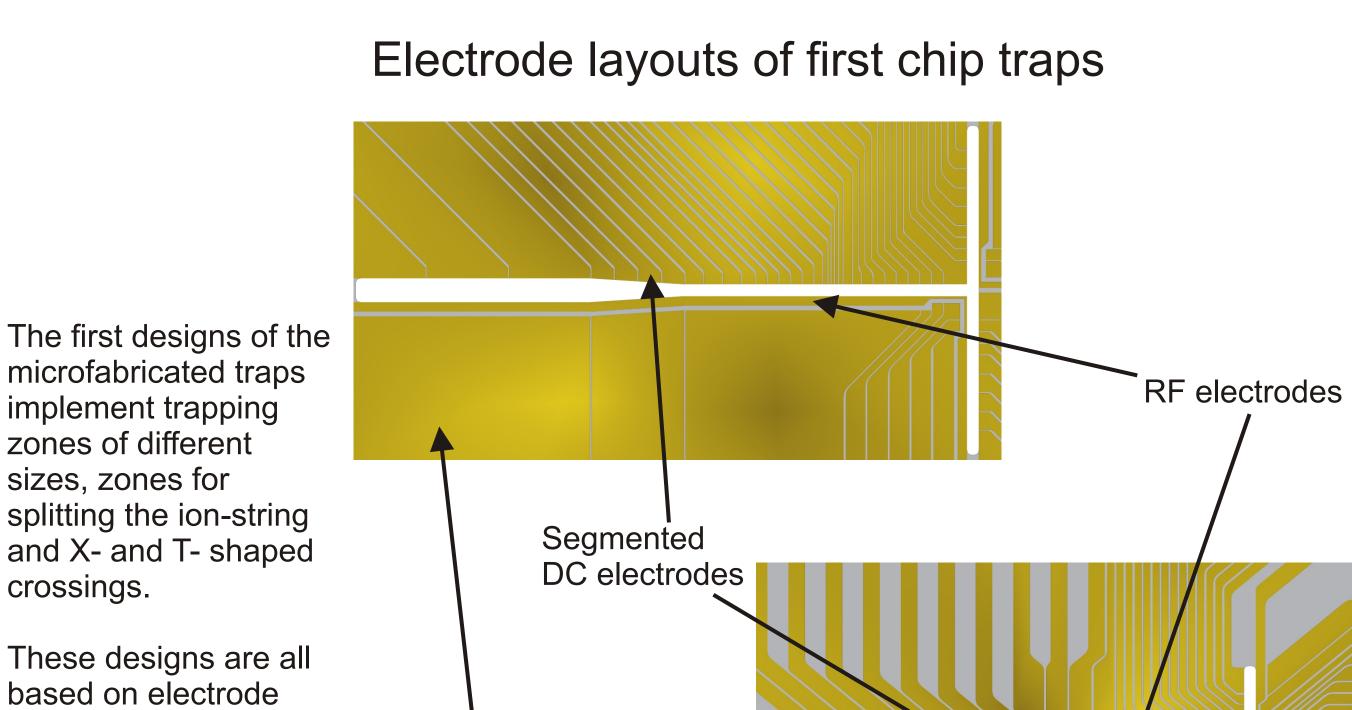


Schematic of a linear Paul trap used for quantum information processing in Innsbruck

Schematic of a microfabricated segmented ion trap with two layers.

Production using standard microfabrication tecniques offers the possibility of precise and complex geometries.



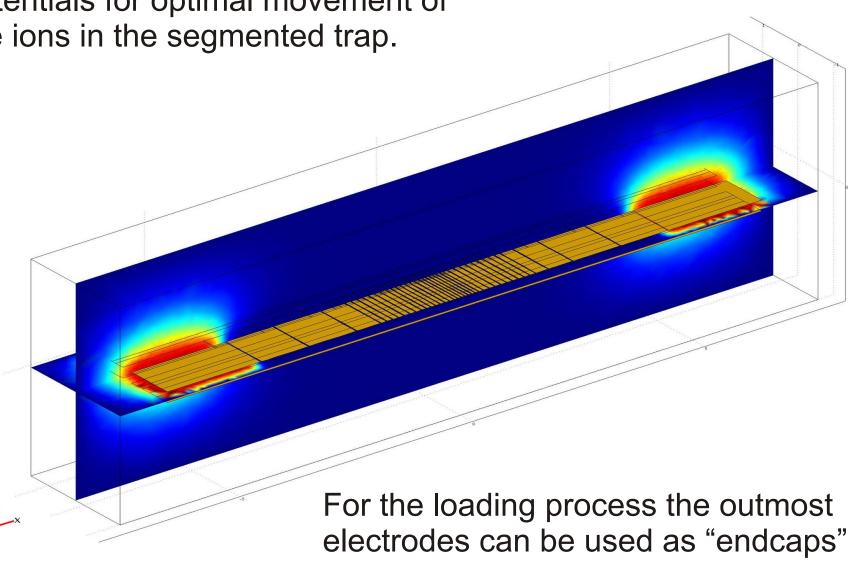


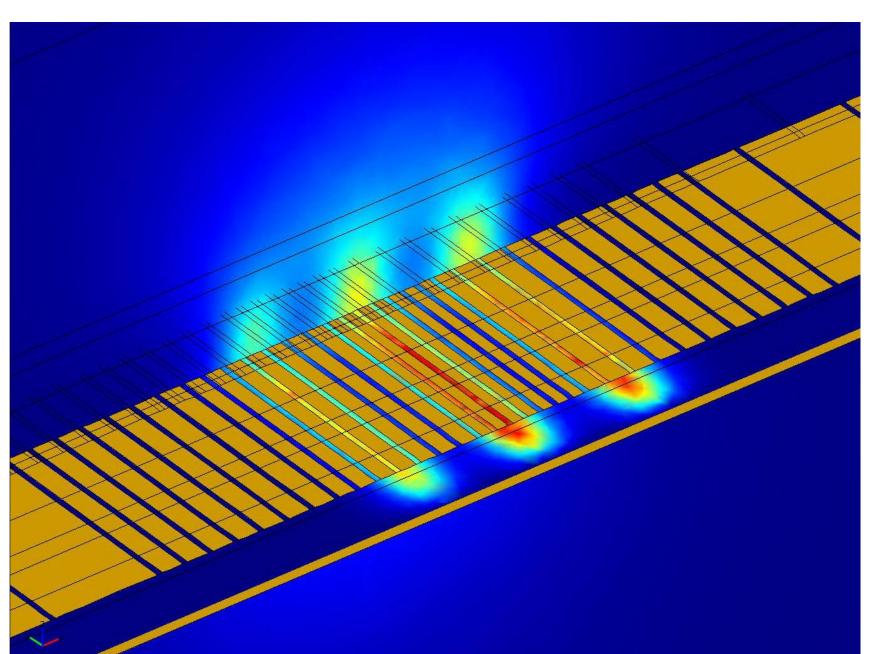
Simulations with COMSOL Multiphysics

COMSOL Multiphysics is a software package suitable for modelling and simulating many physical problems which can be described with partial differential equations. COMSOL Multiphysics uses the Finite Element Method to numerically solve the relevant physical equations.

From the RF and DC field calculations, the axial and radial trapping potentials can be derived, and the trap can be fully characterised.

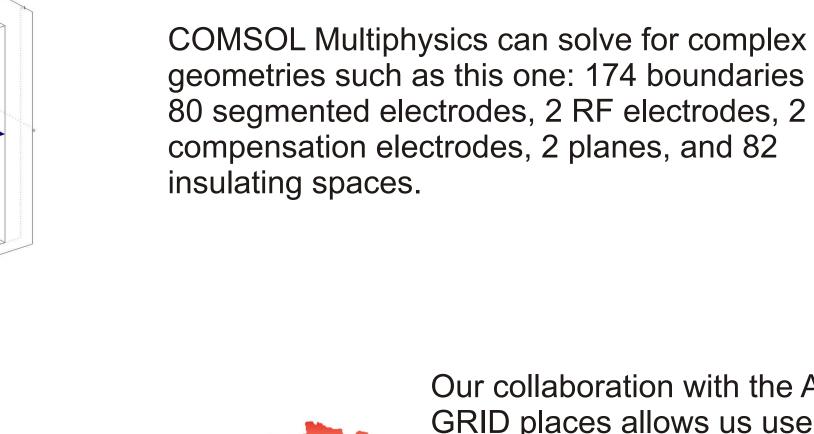
We can simulate the potentials created by the segmented electrodes, and can tailor these potentials for optimal movement of the ions in the segmented trap.





linear segmented trap geometry. The electrodes, which are 2 micron thick in real life, are modelled as two-dimensional structures embedded in a threedimensional space. The entire trap geometry can be modelled in a single file. On the left an exemplary simulation to create two potential wells is shown. -one step in the splitting of an ion string.

Simulation of DC field in a



geometries such as this one: 174 boundaries -80 segmented electrodes, 2 RF electrodes, 2 compensation electrodes, 2 planes, and 82 insulating spaces.



Our collaboration with the Austrian GRID places allows us use of sophisticated computers with large memory resources - crucial for accurate and detailed simulations.

Trap Fabrication

Trap fabrication is completed in collaboration with the Precision Engineering group at the Fraunhofer Institut für Angewandte Optik und Feinmechanik, Jena, Germany.



Electrode fabrication:

Institut **Angewandte Optik** und Feinmechanik



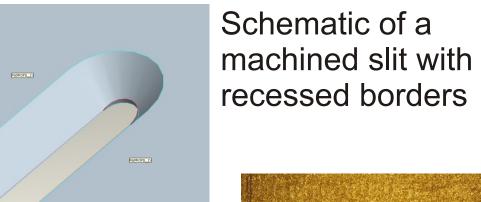
Metalization of substrate material followed by photolithographic etching and ceramic machining.

Assembly:Trap layers and spacers are joined with UHVcompatible epoxy (Epotek 353ND) and assembled with a "fineplacer" to 5 micron

Substrate: Shapal wafer (Aluminium Nitride) meeting the

- following requirements: - high mechanical strength
- low thermal expansion - heat resistance
- capable for UHV conditions

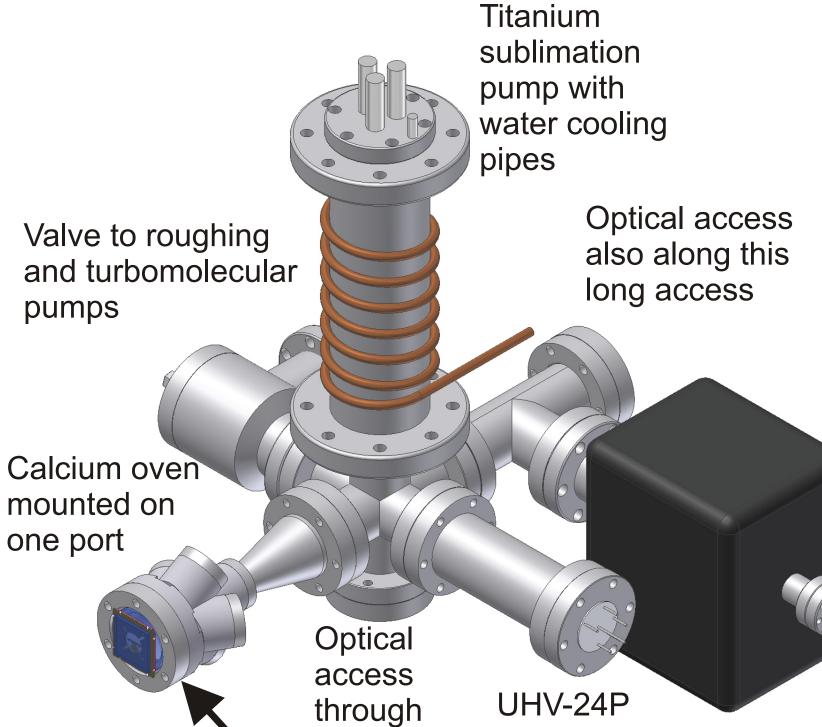
Electrodes: Titanium (0.1 micron) followed by Gold (2 micron) Precision of the structures is +- 5 micron



Exemplary sample with gold layer on AINsubstrate with recessed border



Vacuum apparatus



Multiplexer with

flange.

gauge side ports

pump Connectors and

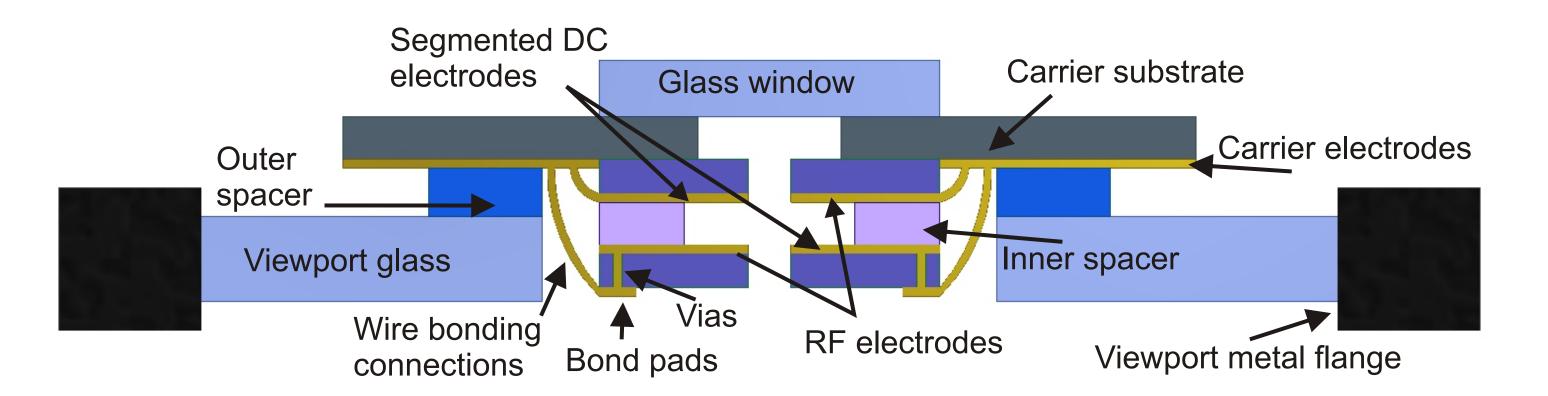
20L/s ion

trap mounted on Multiplexer focus is at centre of filter boards slide flange face onto carrier from the side

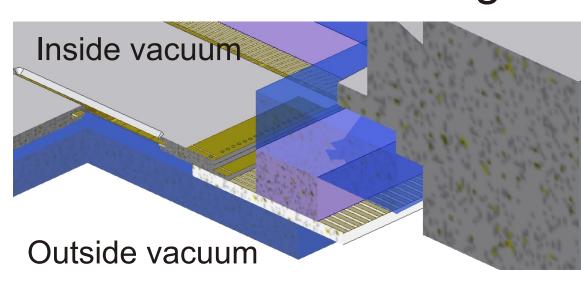
Novel UHV Trap mounting

Cross-sectional view of trap mounted on flange

(Schematic only - not to scale)



Detail of feedthrough



Electrodes for connection to segments pass under the outer spacer. Connection is made vacuum tight with Epotek 353ND epoxy. KEL **USA** connectors with attached filter boards simply slide onto the carrier substrate and are automatically aligned.